

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 117115		APPLICATION NO. New US Application 10/670275	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Mutsumi KIMURA			
				FILING DATE September 26, 2003			

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	

FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
TW	1	JP A 10-125931 (with abstract and translation)	05/15/1998	Japan		
	2	JP A 2002-182582 (with abstract and translation)	06/26/2002	Japan		
	3	JP A 2002-261335 (with abstract and translation)	09/13/2002	Japan		
	4	JP A 2002-314052 (with abstract and translation)	10/25/2002	Japan		
	5	JP A 2002-311858 (with abstract and translation)	10/25/2002	Japan		
	6	JP A 2002-314123 (with abstract and translation)	10/25/2002	Japan		
	7	JP A 2002-343944 (with abstract and translation)	11/29/2002	Japan		
TW	8	JP A 2002-368282 (with abstract and translation)	12/20/2002	Japan		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)						

EXAMINER	DATE CONSIDERED 11/6/04
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: September 26, 2003

Sheet 1 of 1

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TW	1	Shimoda et al, "Surface Free Technology by Laser Annealing (SUFTLA)", IEDM 99-289 pp 12.1.1-12.1.4					
	2	Utsunomiya et al., "36.2: Low Temperature Poly-Si TFTs on Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA TM)", SID 00 DIGEST, pp 916-919					
TW	3	Shimoda, "Future Trend of TFTs", Asia Display/IDW '01, pp 327-330					
	4	Utsunomiya et al. "Low Temperature Poly Si TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA [®])", Asia Display/IDW '01), pp 339-342					
TW	5	Utsunomiya et al. "SUFTLA [®] (Surface Free Technology by Laser Ablation/Annealing), AM-LCD '02, pp 37-40					
EXAMINER				DATE CONSIDERED			
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Date: February 9, 2004